

## **MEMS Probe Card용 Micro Needle 공정 연구**

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### **Plating Process of Micro-needle for MEMS Probe Card**

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**Abstract :** Micro probe with Ni-Co tip was designed. Unit processes for fabricating the micro probe were developed. We are investigated the micro probe tip using by Ni-Co alloy. One-step and three-step needle was fabricated by plating process, CMP, and photolithography process. The plating thickness was varied by current density and time. Futher data will be extract by different process conditions.

**Key Words :** MEMS Probe Card, Micro Needle, Plating